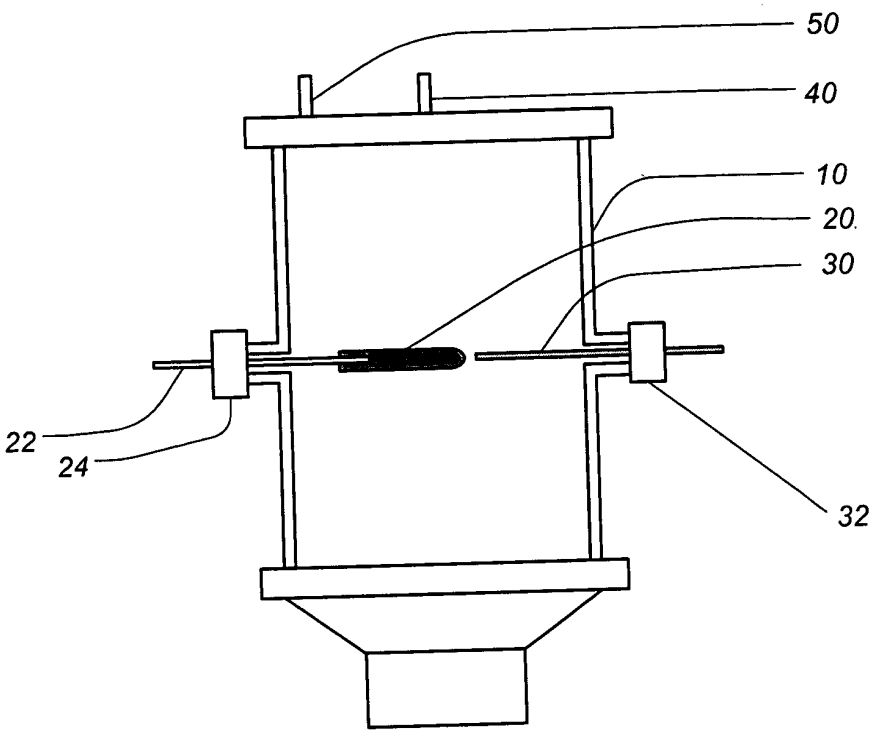
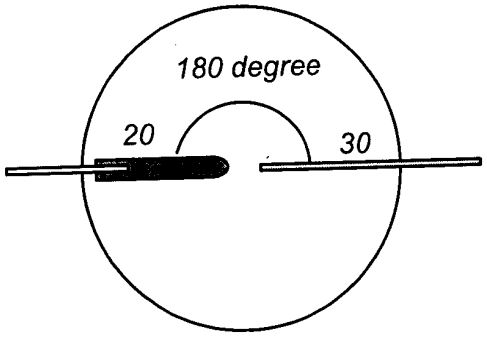
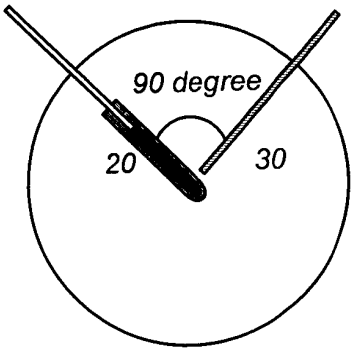


A)



B)



C)

FIG.1.

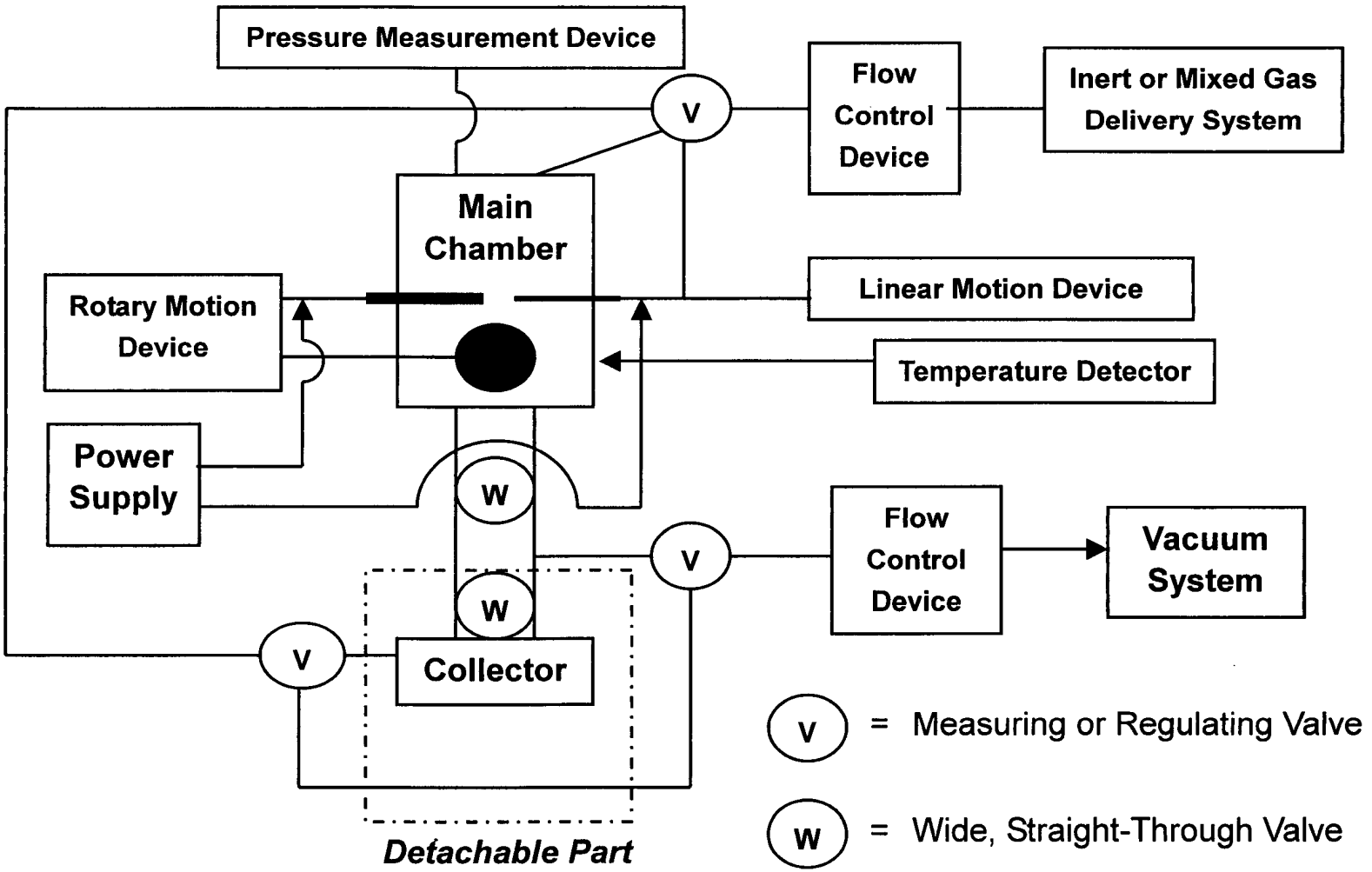

Pressure Measurement Device
V
Flow Control Device
Inert or Mixed Gas Delivery System
Main Chamber
Rotary Motion Device
Linear Motion Device
Temperature Detector
Power Supply
W
Flow Control Device
Vacuum System
V
W
V
Collector
Detachable Part
V = Measuring or Regulating Valve
W = Wide, Straight-Through Valve

FIG. 2.

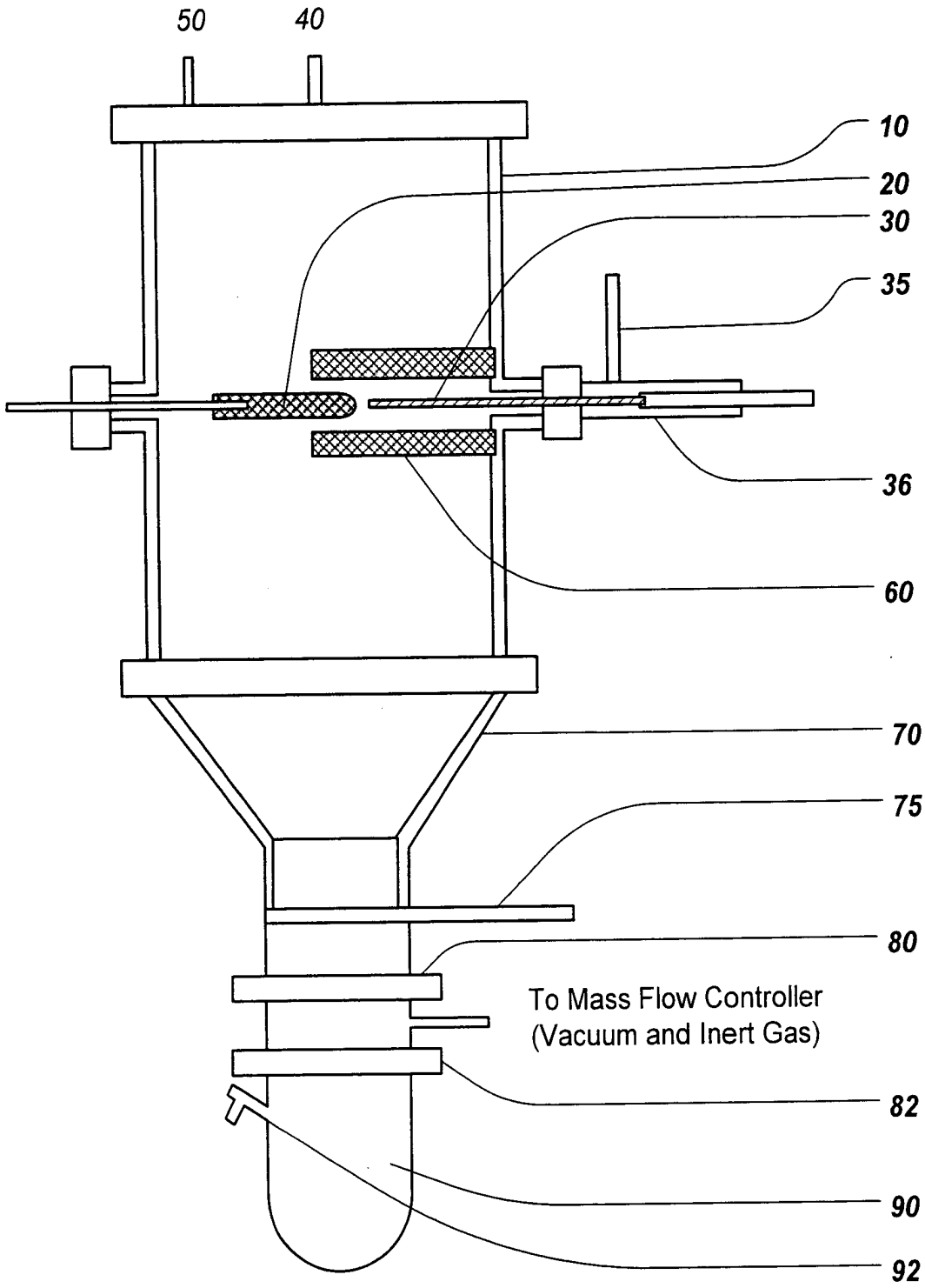

50
40
10
20
30
35
36
60
70
75
80
To Mass Flow Controller
(Vacuum and Inert Gas)
82
90
92

FIG.3.

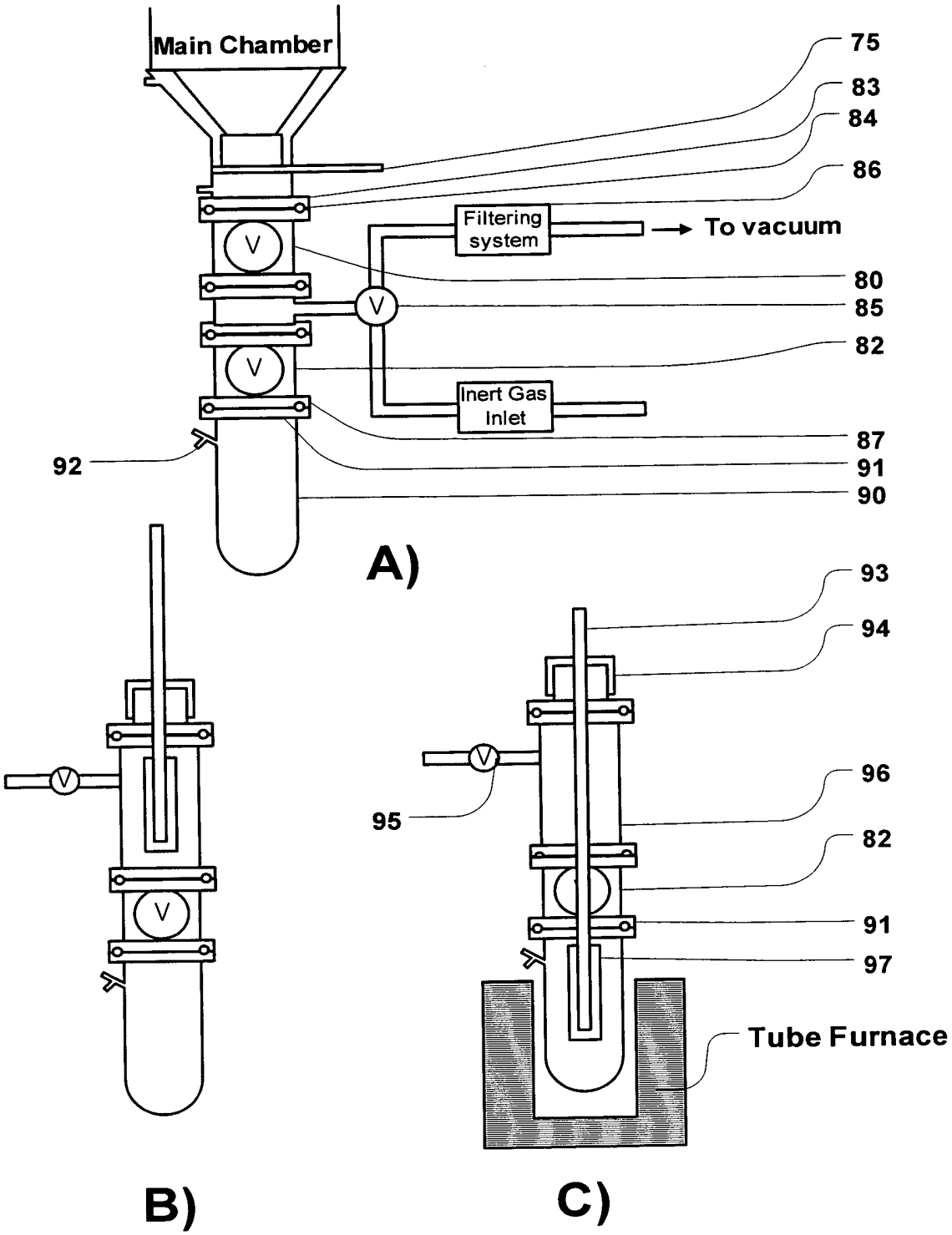
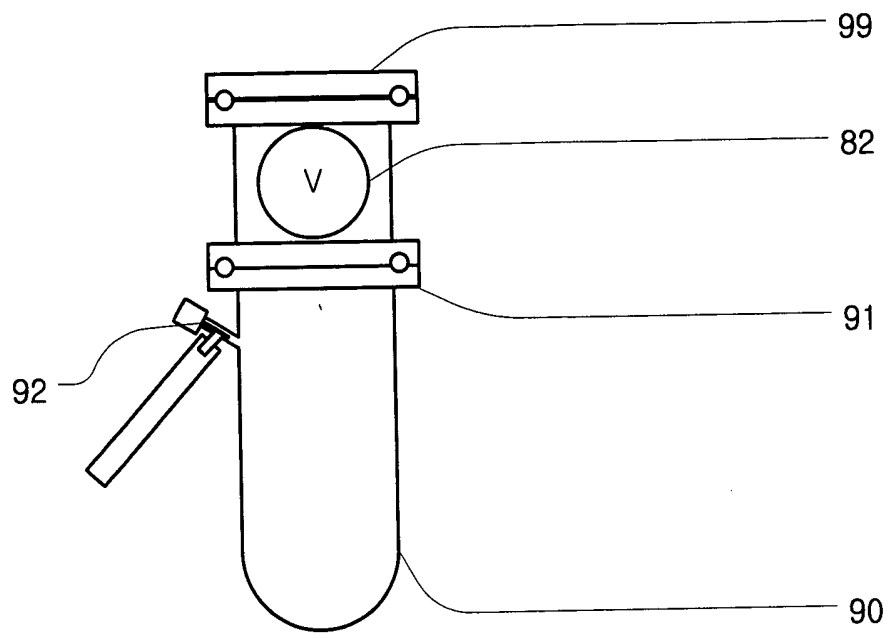
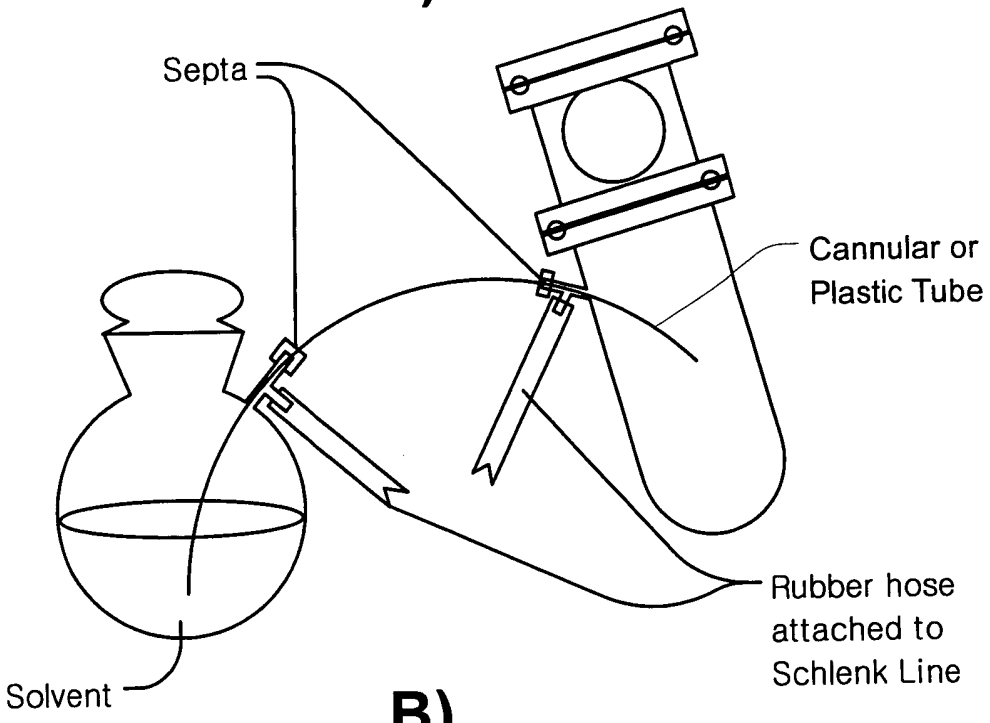

Main Chamber
75
83
84
86
Filtering system
To vacuum
80
85
82
Inert Gas Inlet
87
92
91
90
A)
93
94
96
95
82
91
97
Tube Furnace
B)
C)

FIG.4.


99
82
V
91
92
90

A)


Septa
Cannular or
Plastic Tube
Rubber hose
attached to
Schlenk Line
Solvent

B)

FIG.5.

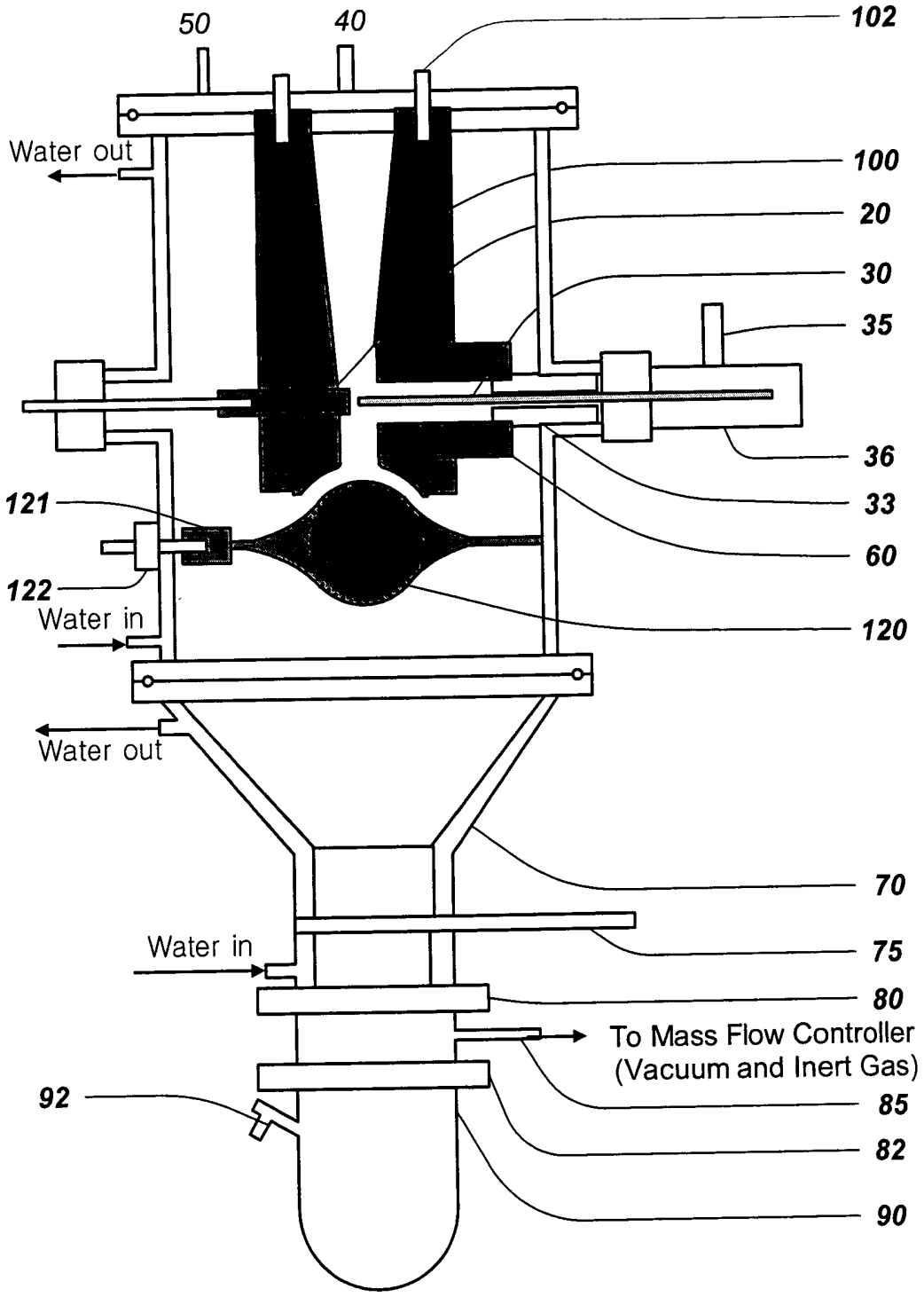
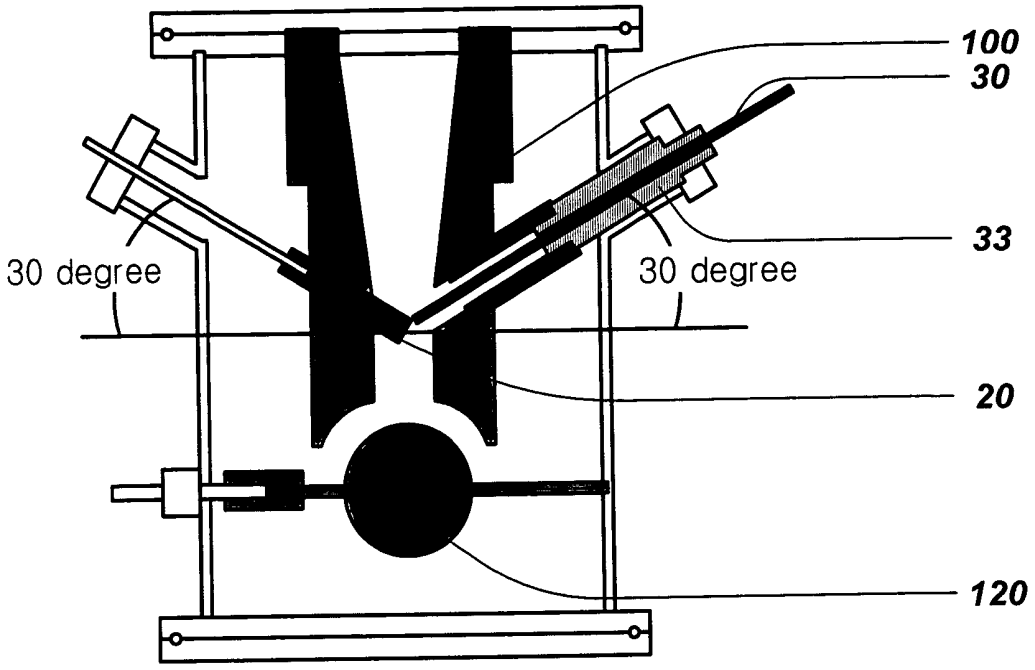
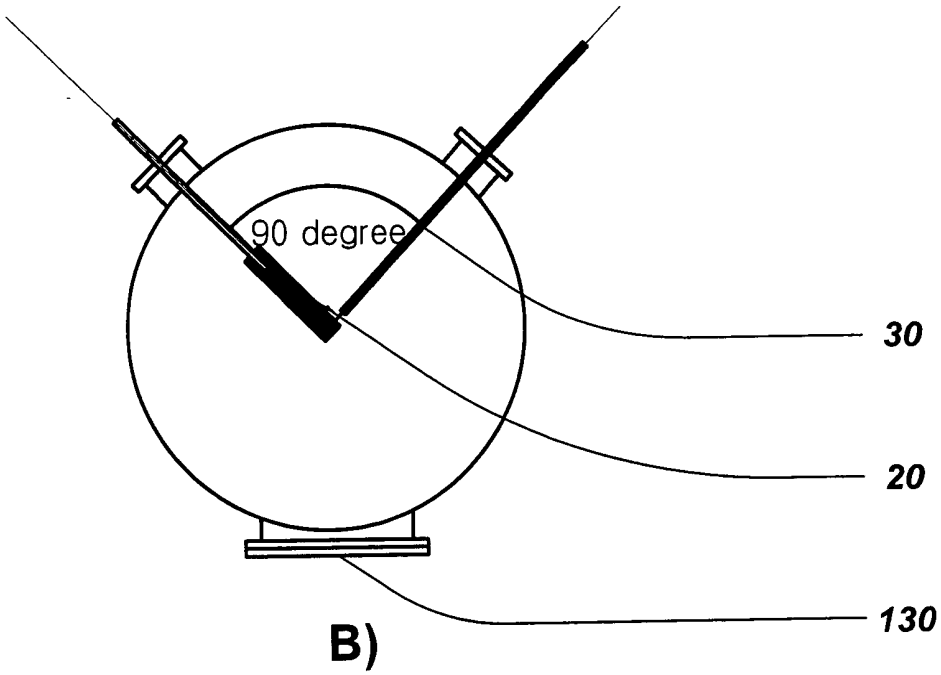

50
40
102
Water out
100
20
30
35
36
121
33
60
122
Water in
120
Water out
70
Water in
75
80
To Mass Flow Controller
(Vacuum and Inert Gas)
92
85
82
90

FIG.6.



A)



B)

FIG.7.

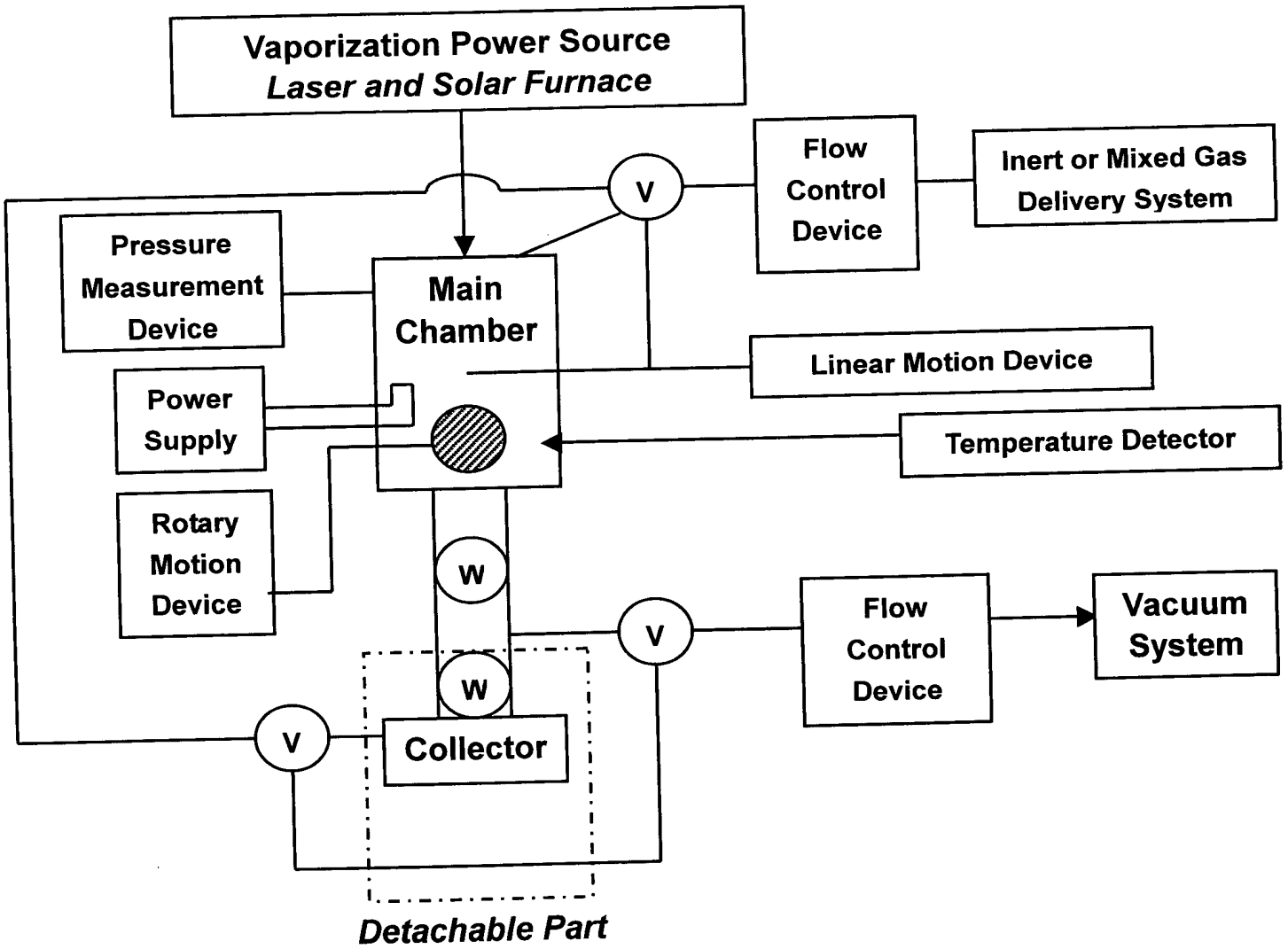
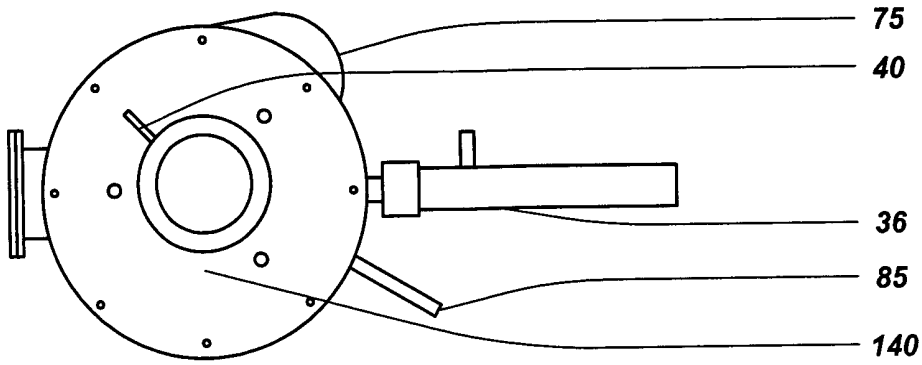
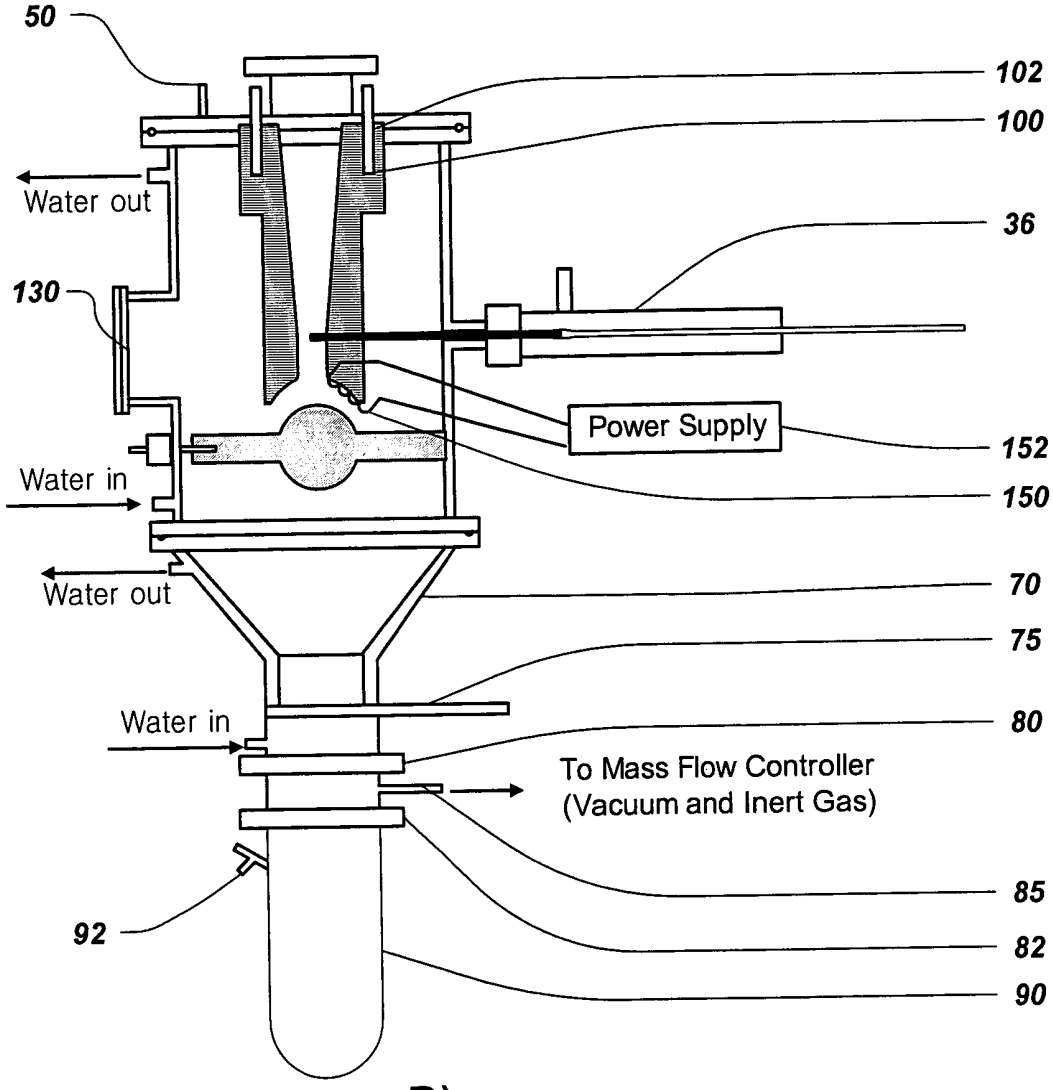

Vaporization Power Source
Laser and Solar Furnace
V
Flow Control Device
Inert or Mixed Gas Delivery System
Pressure Measurement Device
Main Chamber
Linear Motion Device
Power Supply
Temperature Detector
Rotary Motion Device
W
W
V
Flow Control Device
Vacuum System
V
Collector
Detachable Part

FIG.8.


75
40
36
85
140

A)


50
102
100
Water out
36
130
Power Supply
152
Water in
150
Water out
70
75
Water in
80
To Mass Flow Controller
(Vacuum and Inert Gas)
85
92
82
90

B)

FIG.9.